2022년 1월 25일(화), 10:45-12:30 Room K (다이아몬드 I, 6층)

F. Silicon and Group-IV Devices and Integration Technology 분과 [TK2-F] 2D Device Technology

좌장: 김경록 교수(UNIST), 이용규 마스터(삼성전자)

| 작성: 삼성속 포구(UNIST), 이용규 마끄디(삼성천자) | |
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| TK2-F-1 10:45-11:15 | 2D Materials based Atomic Memory and RF Switches Myungsoo Kim Department of Electrical Engineering, UNIST |
| TK2-F-2 11:15-11:30 | MoS ₂ Thin-Film Transistor with the Gate Stack of Metal-Ferroelectric(Hf _{0.5} Zr _{0.5} O)-Insulator(Al ₂ O ₃) Gisu Youm and Changhwan Shin Department of Electrical and Computer Engineering, Sungkyunkwan University |
| TK2-F-3 11:30-11:45 | Effective Work-function Increase Observed in Al/SiO ₂ /Si Junction with Graphene Interlayer at Al/SiO ₂ Interface Wonho Song ¹ , Jung-Yong Lee ² , Junhyung Kim ¹ , Jinyoung Park ¹ , Eunseok Hyun ¹ , and Kibog Park ^{1,3} **Department of Physics, UNIST, ² SKKU Quantum Information Research Support Center, Sungkyunkwan University, ³ Department of Electrical Engineering, UNIST |
| TK2-F-4 11:45-12:00 | Experimental Study of the Impact of Hf _{0.5} Zr _{0.5} O ₂ Film Deposition Temperature on Endurance Characteristics Hyeonjung Park, and Changhwan Shin Department of Electrical and Computer Engineering, Sungkyunkwan University |
| TK2-F-5 12:00-12:15 | Highly Reliable Electrical Extraction of Density of Grain Boundary States from the Ultrathin Poly-Si MOSFET Channel Inyoung Lee ¹ , Kyung Song ² , Seungmin Lee ³ , Il Hwan Cho ¹ , and Seongjae Cho ³ ¹ Department of Electronic Engineering, Myongji University, ² Materials Modeling and Characterization Department, KIMS, ³ Department of Electronic Engineering, Gachon University |
| TK2-F-6 12:15-12:30 | Impact of Plasma Power on Slow Trap Density in Al₂O₃/GeO₂/Ge Structure 이진우, 한승민, 안대환, 한재훈 <i>KIST</i> |